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| Form PTO 1449 (Modified) | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY DOCKET NO. 241584US0CONT | | SERIAL NO. 10/642618 New Application | |
| LIST OF REFERENCES CITED BY APPLICANT | | | | APPLICANT Hideaki SAKURAI, et al. | | | |
| | | | | FILING DATE Herewith 8-19-03 | | GROUP 2813 | |
| | | | | U.S. PATENT DOCUMENTS | | | |
| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUB CLASS | FILING DATE IF APPROPRIATE |
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| | AC | 5,462,922 | 10-1995 | DOI, ET AL. | — | | |

FOREIGN PATENT DOCUMENTS

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| | | | | | YES | NO |
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| <i>↓</i> | AE | 2000-331601A | 11-2000 | JAPAN | | |
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| <i>↓</i> | AP | 10-182861 | 07-1998 | JAPAN (w/English Abstract) | | |

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

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| <i>DS</i> | AQ | Vossen, John L., "Thin Film Process", Academic Press, 1978, Pages 438-439. | |
| <i>↓</i> | AR | H., Seehase, "Plasma Display Panel MgO Thin Film Properties and Their Modification by Low Energy Ion Bombardment", Displays, January 1985, Pages 21-34. | |
| | AS | Monthly Semiconductor World, [3], 1998, Pages 121-123. | |
| | AT | Excalibur Paper Phase Cleaning System Described in the Catalog of MFSI Co., Ltd. | |
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| | AV | M.N. Abraham, et al., "Growth of High Purity and Doped Alkaline Earth Oxides: I. MGO and CaO", The Journal of Chemical Physics, 35[8], 1971, Pages 3752-3756. | |
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| | AX | Lee, W.T., "Study of Protective Layers in AC-PDPs", IDW 99, Pages 763-766. | |
| | AY | "Preparation of MgO Protective Films for Plasma Display Panels Using Vacuum Deposition Methods", ULVAC Technical Journal, No. 46, 1997, Pages 8-13. | |
| <i>↓</i> | AZ | "Cathode Materials for Color Plasma Displays", O Plus E, February 1996. | <input type="checkbox"/> Additional References sheet(s) attached |
| Examiner | | <i>DS</i> | |
| | | Date Considered 11/2/04 | |

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.